



## **Pivotal Introduces Industry's First In Situ Leak Detection Product for CVD Systems**

**PIVOTAL'S LEAKDETECT™ IDENTIFIES ATMOSPHERIC MICRO-LEAKS DURING WAFER PROCESSING**

**Pleasanton, CA.—March 10, 2006**—Pivotal Systems Corporation today announced the release of its LeakDetect™ product for in situ detection of atmospheric leaks in CVD vacuum systems with multiple repeat orders from leading IDMs. The product is an industry first in its ability to deliver a high sensitivity leak detection solution in situ, during wafer processing.

“As CDs and film thicknesses scale to smaller technology nodes, CVD processes are increasingly susceptible to small atmospheric leaks. “A number of customers have come to us with a need for in situ leak detection because they have recently experienced multi-million dollar scrap events. These micro-leaks were not an issue at larger nodes, but now they often go unnoticed until end of line yield,” said Mukund Venkatesh, Pivotal Vice President of Marketing and Business Development, “Pivotal’s LeakDetect system monitors the wafer processing environment at all times, alarming the tool and equipment engineers immediately if a leak is detected.”

The LeakDetect system combines available optical emission spectroscopy (OES) technology with proprietary algorithms and software to deliver a highly sensitive real-time production solution. “Because it is real-time and always on during wafer processing, we are learning about leaks that occur momentarily; for example, when a slit valve opens or closes. Our traditional off-line helium leak detector approaches would not have detected these types of leaks, which have caused serious yield excursions,” noted a senior equipment technologist within a leading memory IDM that has adopted Pivotal’s LeakDetect solution.

“We expect this solution to become more and more important over time at each technology node shrink as the threshold for leak levels falls lower and lower,” said Joseph Monkowski, President and Chief Executive Officer at Pivotal Systems.

### **About Pivotal Systems**

Pivotal Systems Corporation provides best-in-class monitoring and process control technology for the semiconductor manufacturing industry. Pivotal’s vision is to enable an order of magnitude increase in fab productivity and capital efficiency for current and future technology nodes. This vision is achieved through its real time in situ process monitoring and control solutions. Founded in 2003 and based in Pleasanton, California, the company is led by veterans from the semiconductor and high-tech industries. For more information about Pivotal, please visit [www.pivotalsys.com](http://www.pivotalsys.com), or send an email to [info@pivotalsys.com](mailto:info@pivotalsys.com).